

**APPARATUS AND METHOD FOR USE IN TESTING A SEMICONDUCTOR
WAFER**

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ABSTRACT

The present disclosure relates to an apparatus for use with a probe station in the testing of semiconductor wafers. In one embodiment, an apparatus for testing semiconductor devices includes a first plate and a second plate. The first plate is configured to be mounted to and completely removable from the head stage of a probe station. The second plate is configured to be removably coupled to the first plate and has a major aperture for receiving a probe-card assembly. Docking equipment desirably is mounted to a major surface of the second plate to facilitate docking of a tester to the probe station.

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